



162162

ABSTRACT OF THE DISCLOSURE

DELAMINATION DRYING APPARATUS AND METHOD

5

An apparatus for delamination drying a substrate is provided. A chamber for receiving a substrate is provided. A chuck supports and clamps the substrate within the chamber. A temperature controller controls the temperature of the substrate and is able to cool the substrate. A vacuum pump is in fluid connection with the chamber. A tilting
10 mechanism is able to tilt the chuck at least 90 degrees.

Fig. 2A



G00002